Atty. Docket: 29926/39496
Title: Batch Type Atomic Layer Deposition Apparatus and In-Situ Cleaning Method Thereof

Inventor: Hyug-Jin Kwon Sheet 1 of 6 (figs. 1 & 2)

FIG. 1 (PRIOR ART)

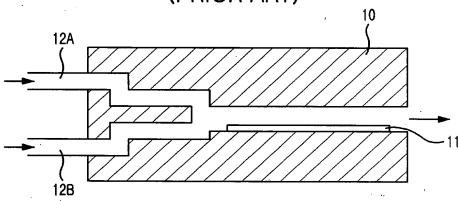
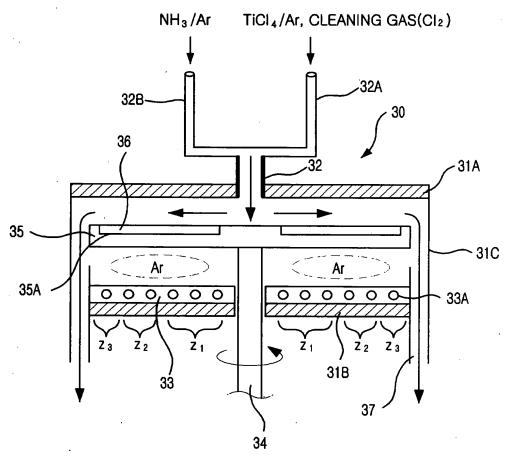


FIG. 2 (PRIOR ART)



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FIG. 3A (PRIOR ART)

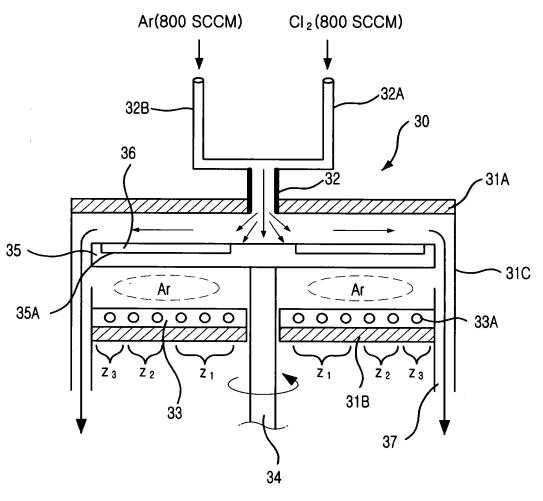
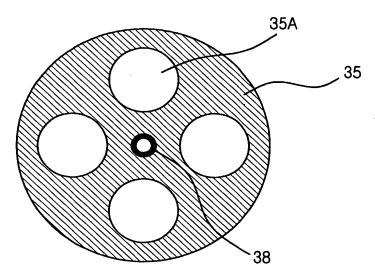


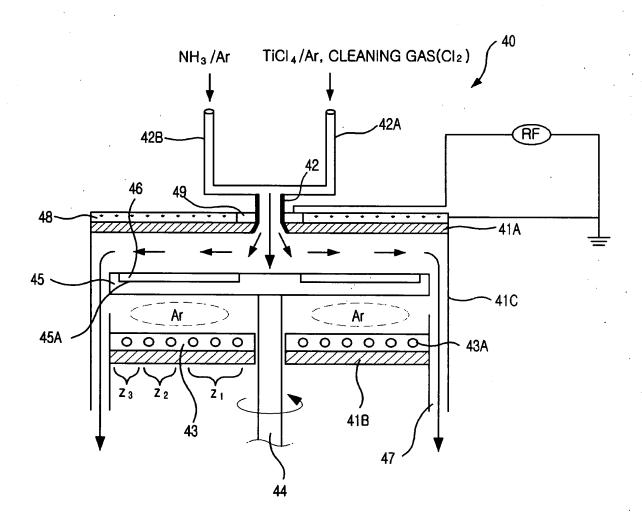
FIG. 3B (PRIOR ART)



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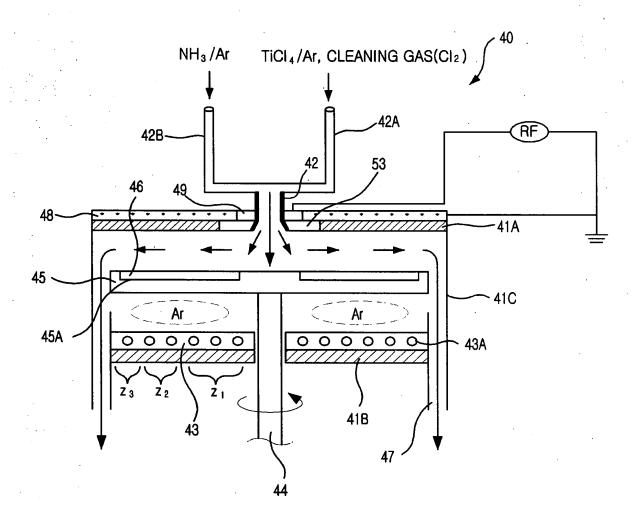
FIG. 4



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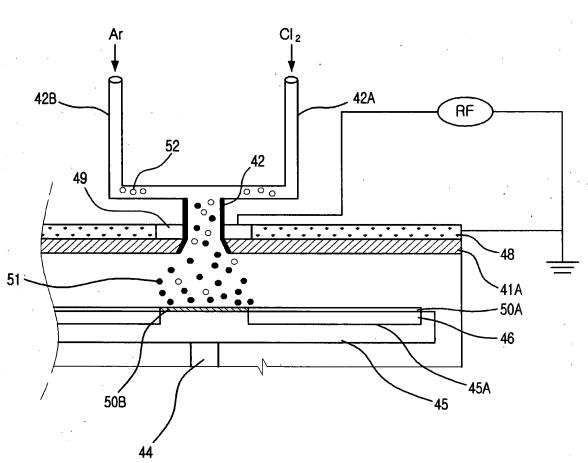
Sheet 4 of 6 (fig. 5)

FIG. 5



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FIG. 6



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FIG. 7

